

FIG.1

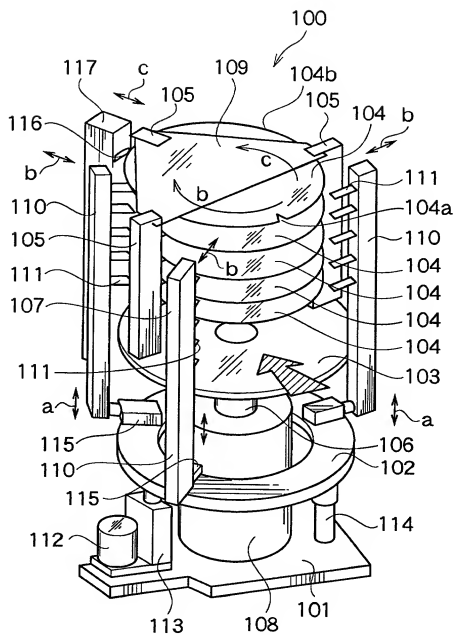


FIG.2

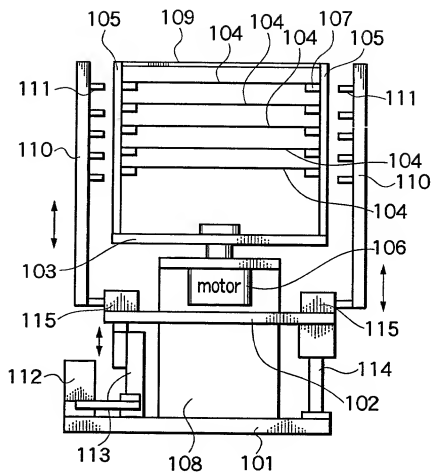


FIG.3A

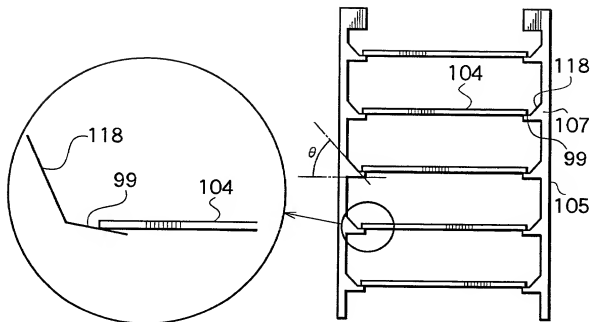


FIG.3B

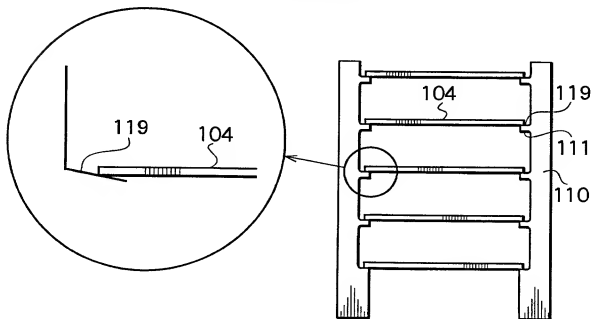


FIG.4

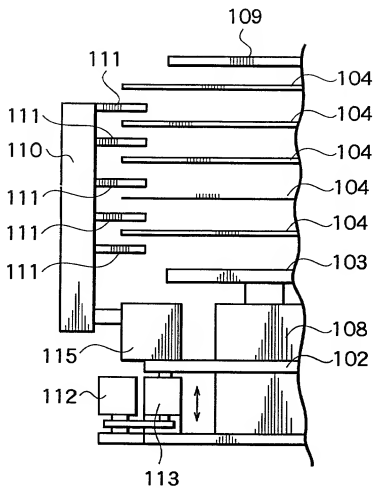


FIG.5A

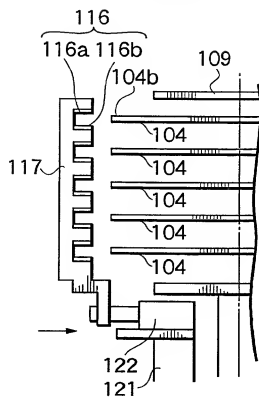


FIG.5B

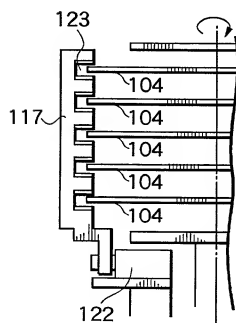


FIG. 6A

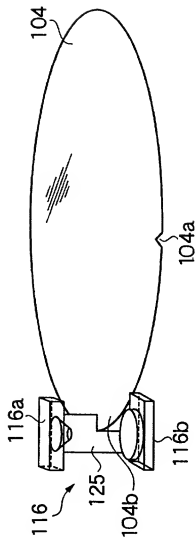


FIG. 6B

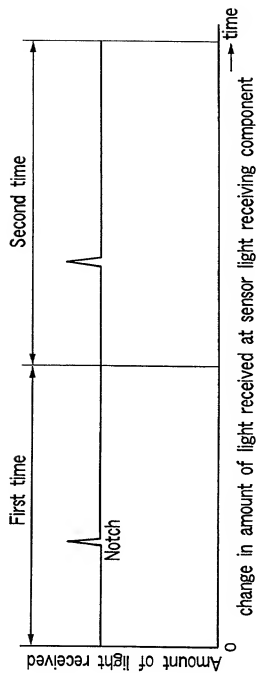








FIG.9

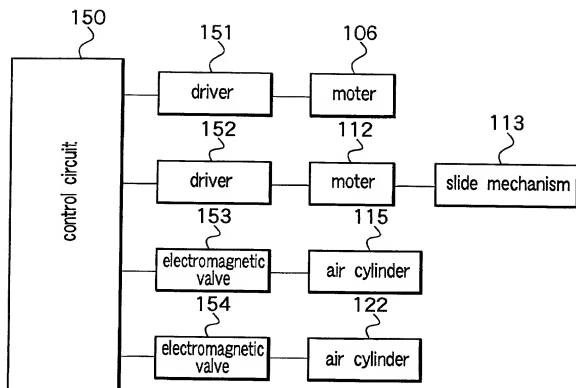


FIG.10A

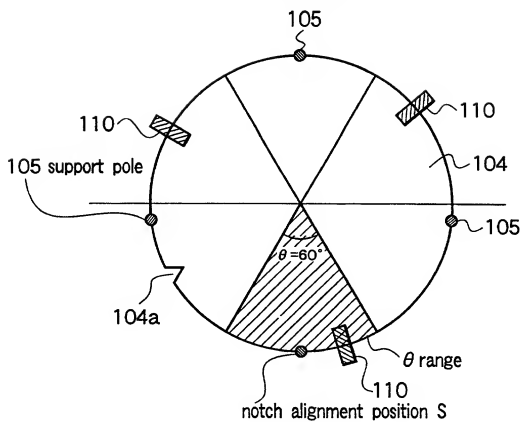


FIG.10B

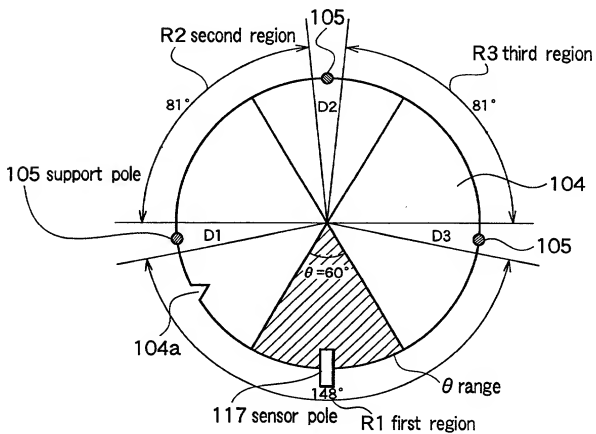


FIG.11

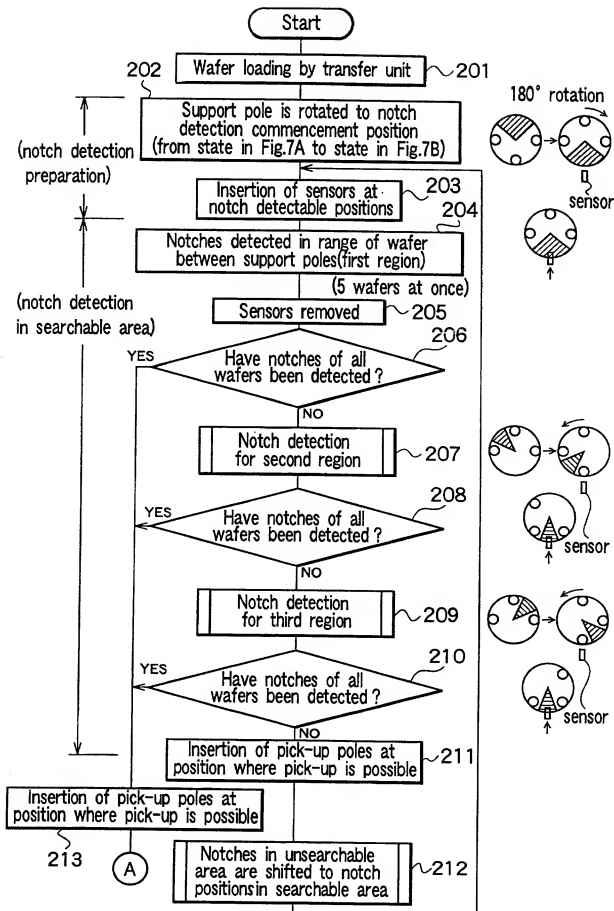


FIG.12

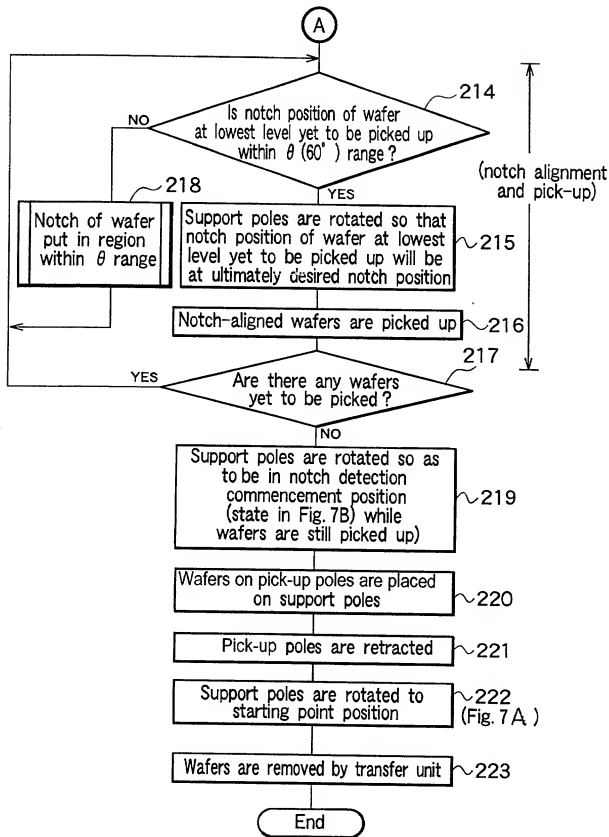


FIG.13A

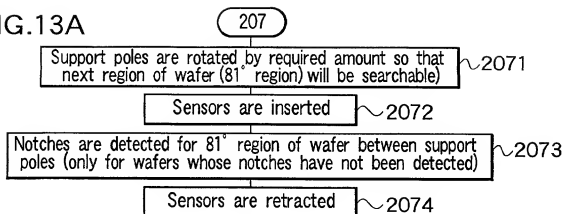


FIG.13B

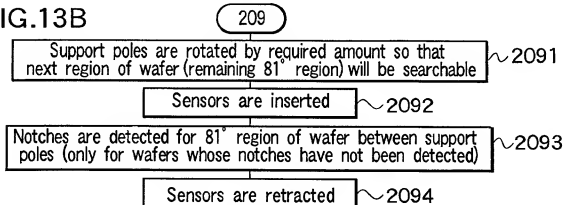


FIG.13C

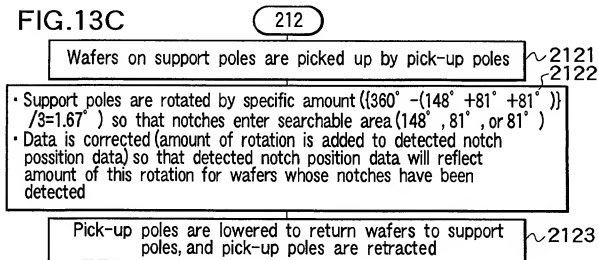


FIG.13D

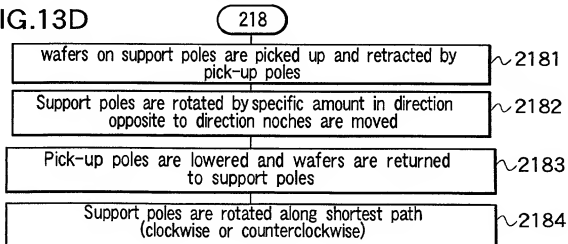


FIG.14A

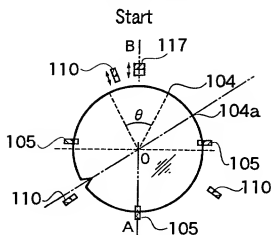


FIG.14D

Support pole rotation

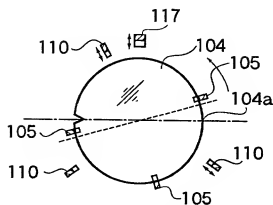


FIG.14B

Just support poles rotated  
wafer retraction

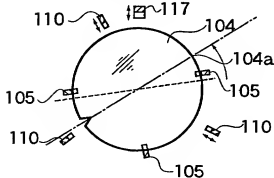


FIG.14E

Wafer rotation

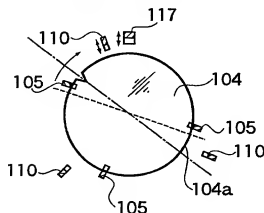
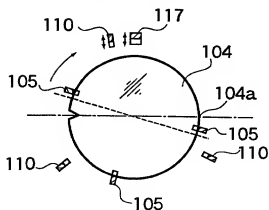


FIG.14C

Wafer rotation



————— Wafer rotation transition  
----- Support pole rotation transition

FIG.15

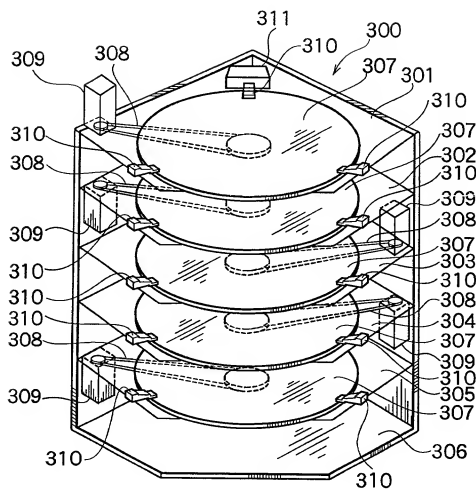


FIG.16B

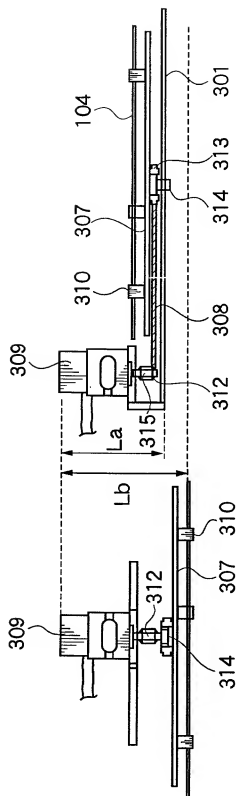


FIG.16A

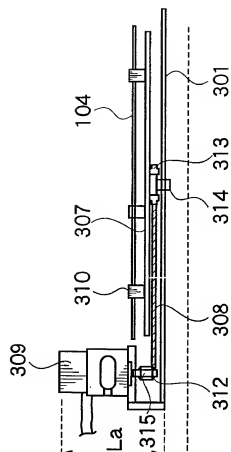
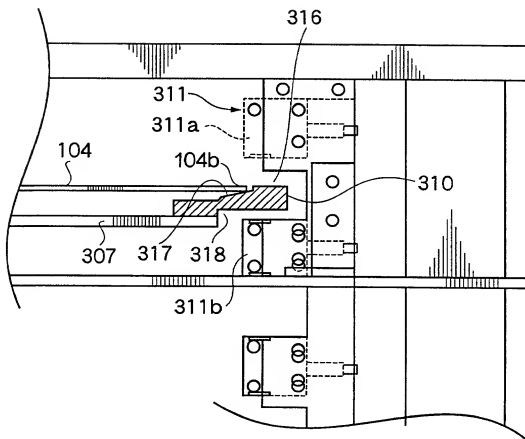




FIG.17



Relationship between support pins and notch detection sensors

FIG.18

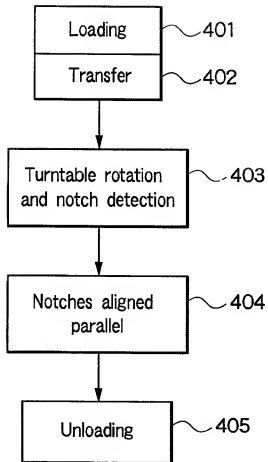


FIG.19A

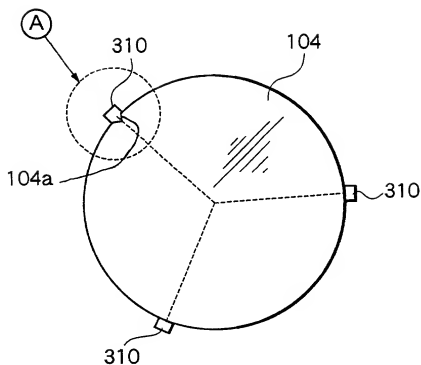


FIG.19B

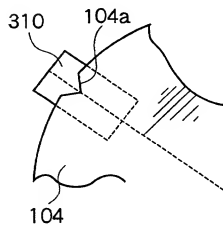


FIG.20A

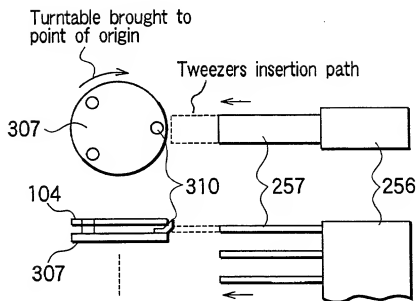


FIG.20B

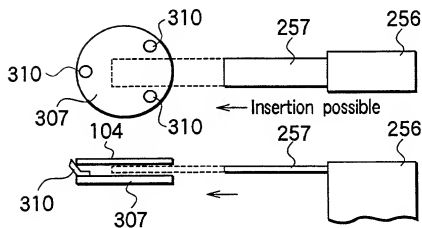


FIG.21

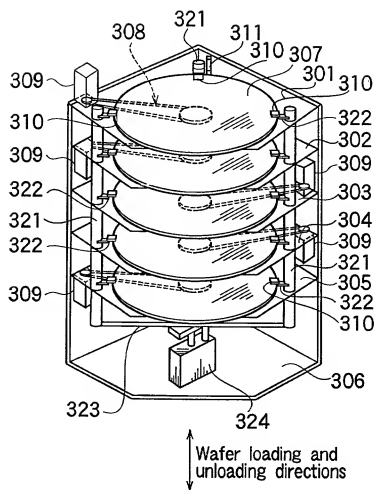


FIG.22A

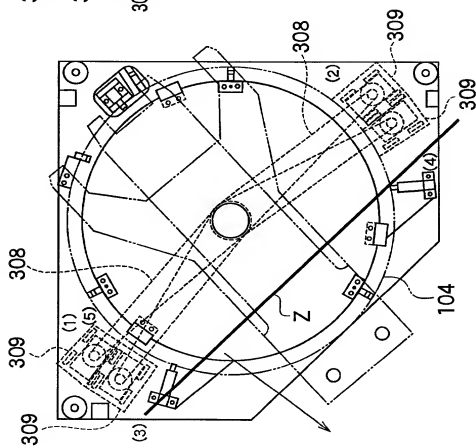


FIG.22B

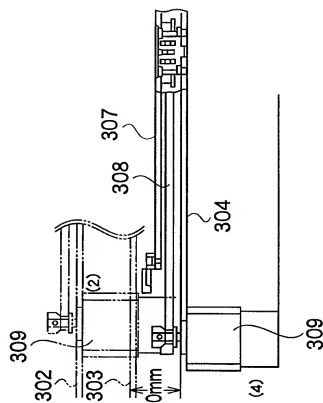


FIG.23A

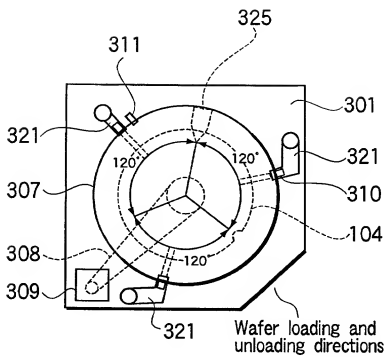


FIG.23B

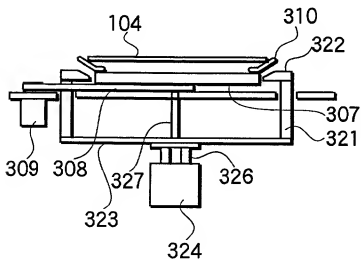


FIG.24

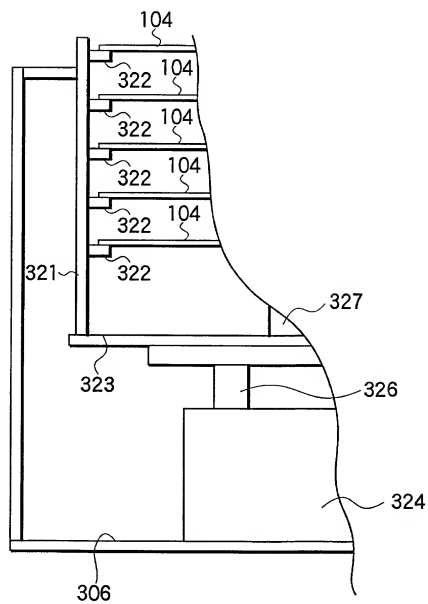




FIG.25A

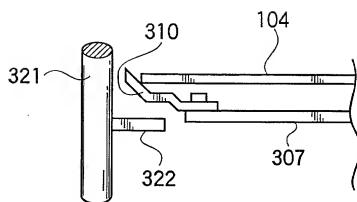


FIG.25B

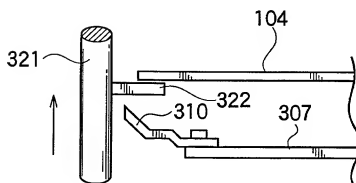


FIG.26

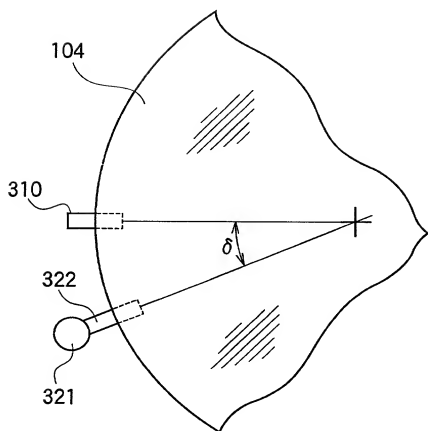


FIG.27

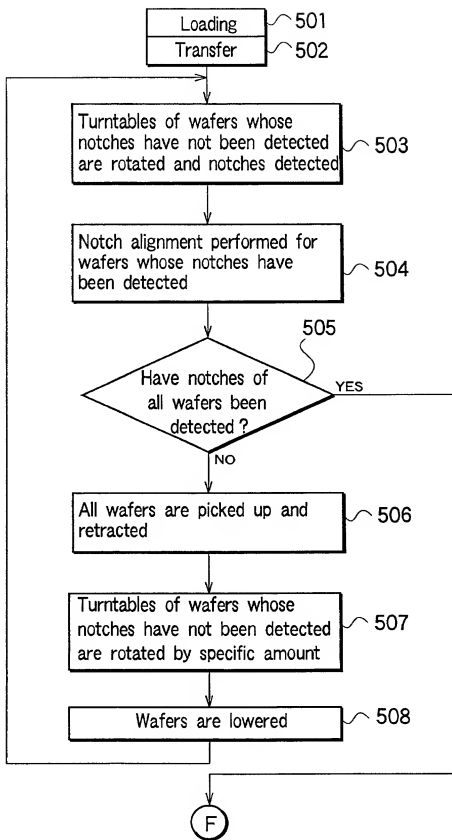


FIG.28

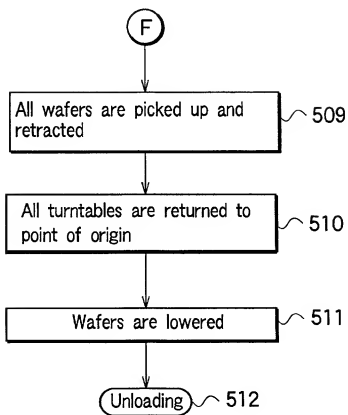


FIG.29

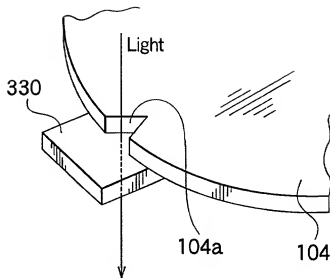


FIG.30A

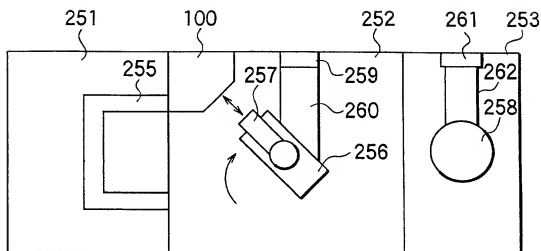


FIG.30B

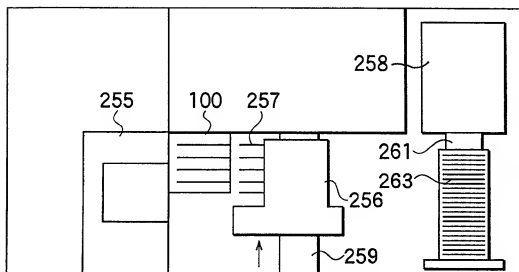


FIG.30C

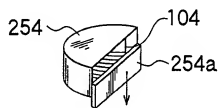


FIG.31

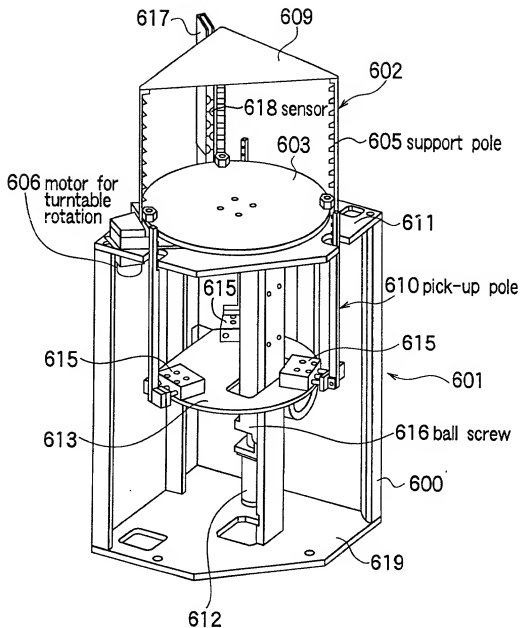


FIG.32

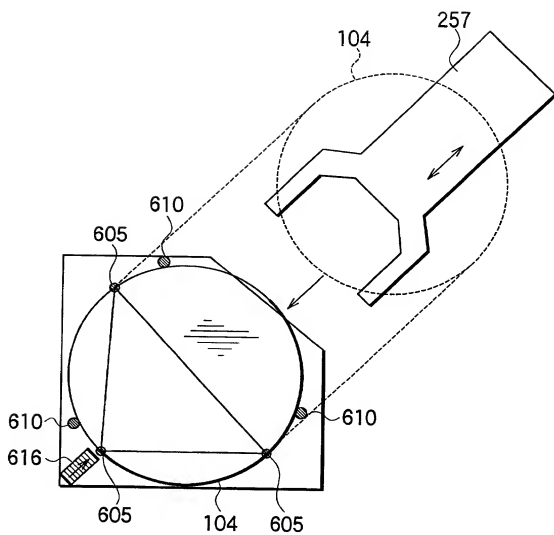




FIG.33

